

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	Examiner: P. B. Kim
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Kazuo IIZUKA et al.)	Group Art Unit: 2851
	:	
Application No.: 10/762,481)	Confirmation No.: 4938
	:	
Filed: January 23, 2004)	Allowed: September 7, 2006
	:	
For: PROJECTION EXPOSURE)	September 22, 2006
APPARATUS	:	

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

STATEMENT REGARDING SUBSTANCE OF THE INTERVIEW

Sir:

Applicants wish to thank the Examiner for the courtesies extended toward their representative during a telephone conversation of August 21, 2006, which was reported in the Interview Summary dated August 24, 2006, in the above-identified application. The Examiner and Applicants' representative discussed that the invention is directed to the exposure of a large substrate with repeated exposure by moving the member n times the pitch of the column, where n is less than the number of columns. The Examiner agreed to reconsider the rejection based on Applicants' explanation.

Applicants' undersigned representative may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "Steven E. Warner", is written over a horizontal line.

Attorney for Applicants
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